

JSR Multi-layer Hardmask

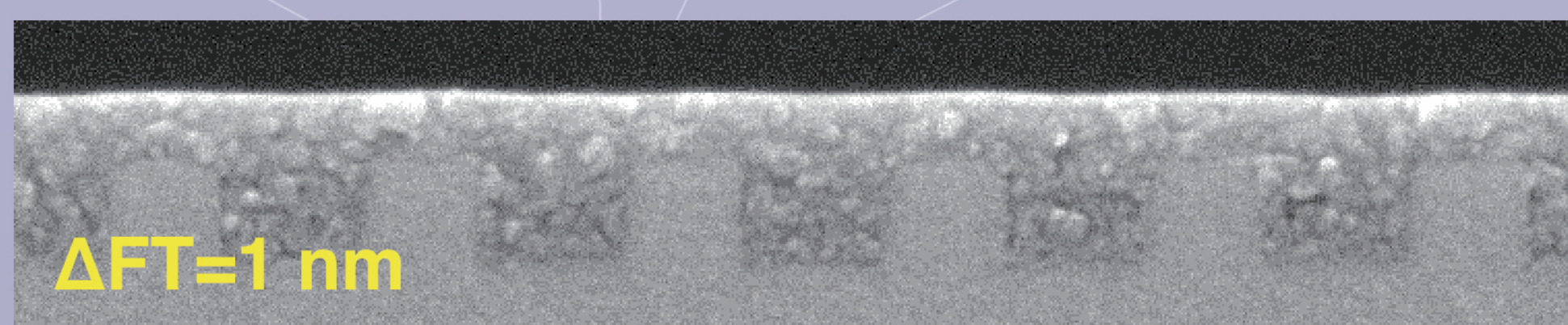
Planarization and Gap-filling UDL for Topography Process

Planarization

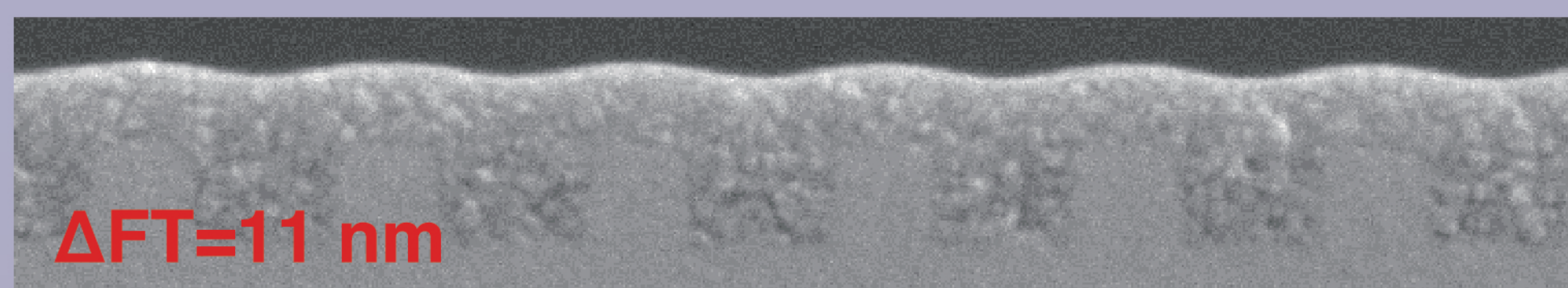
100 nm Open Area



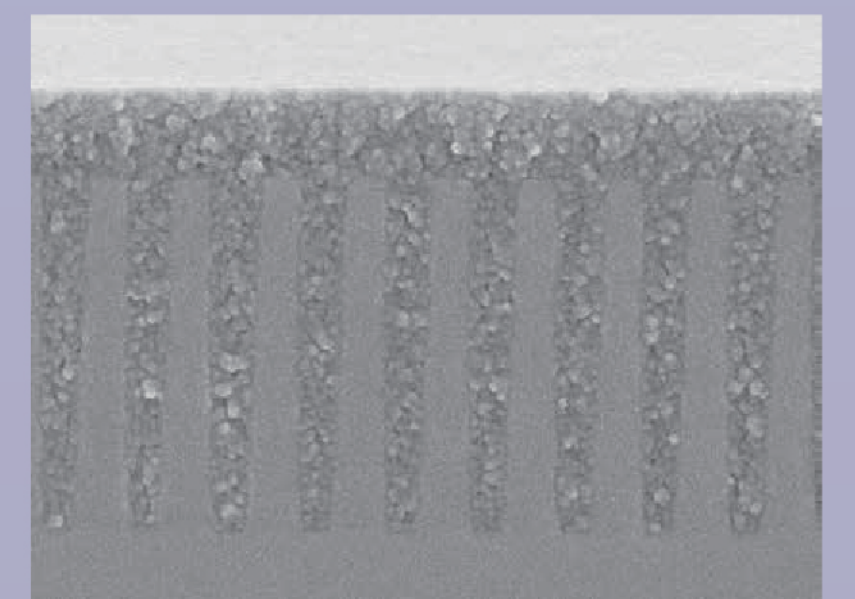
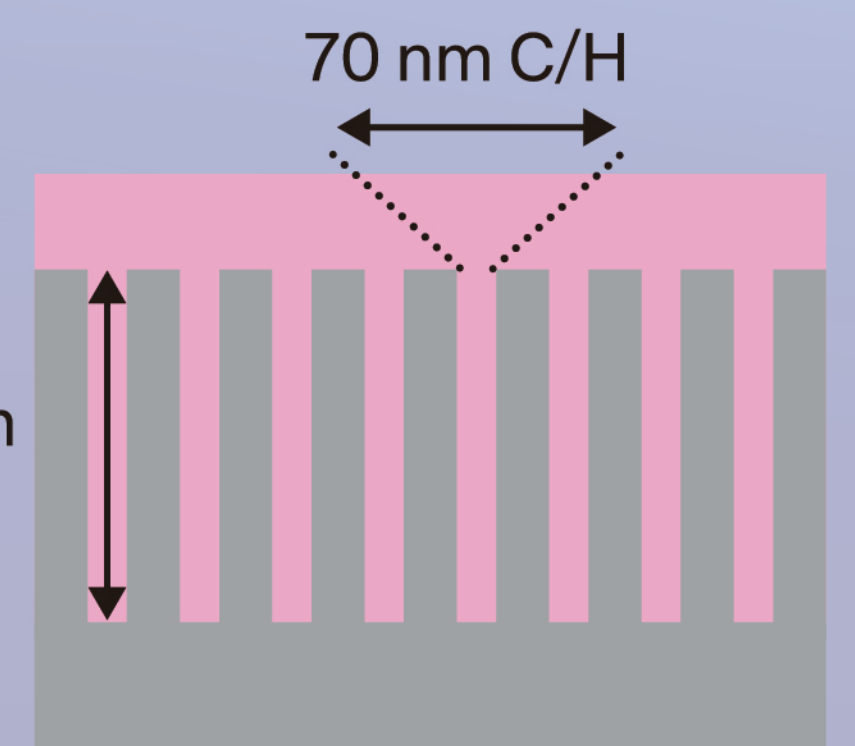
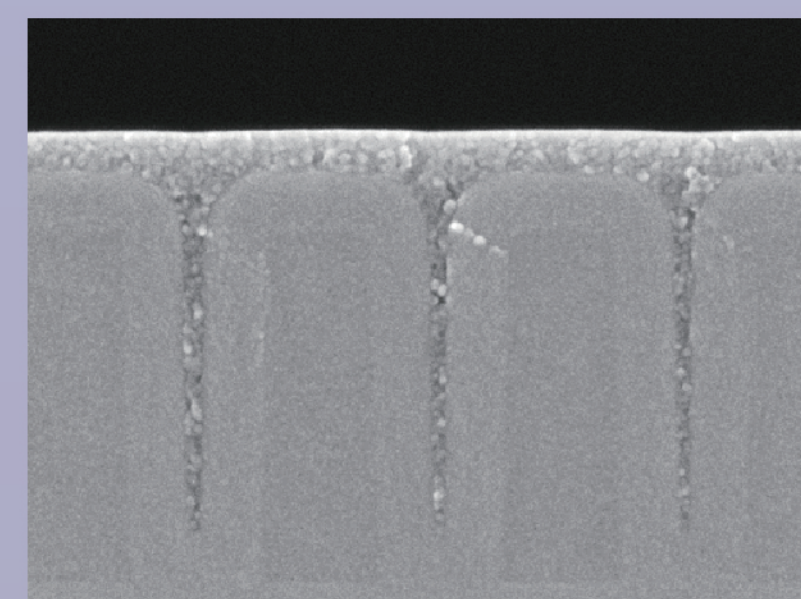
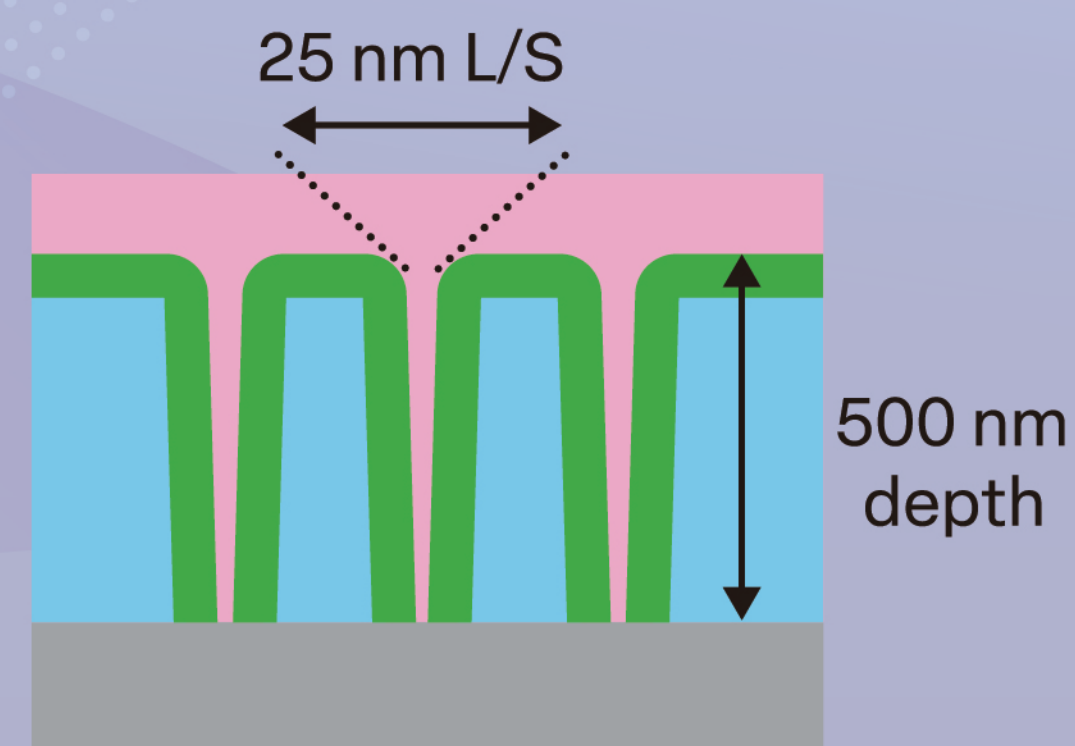
◆ Latest UDL



◆ Standard UDL



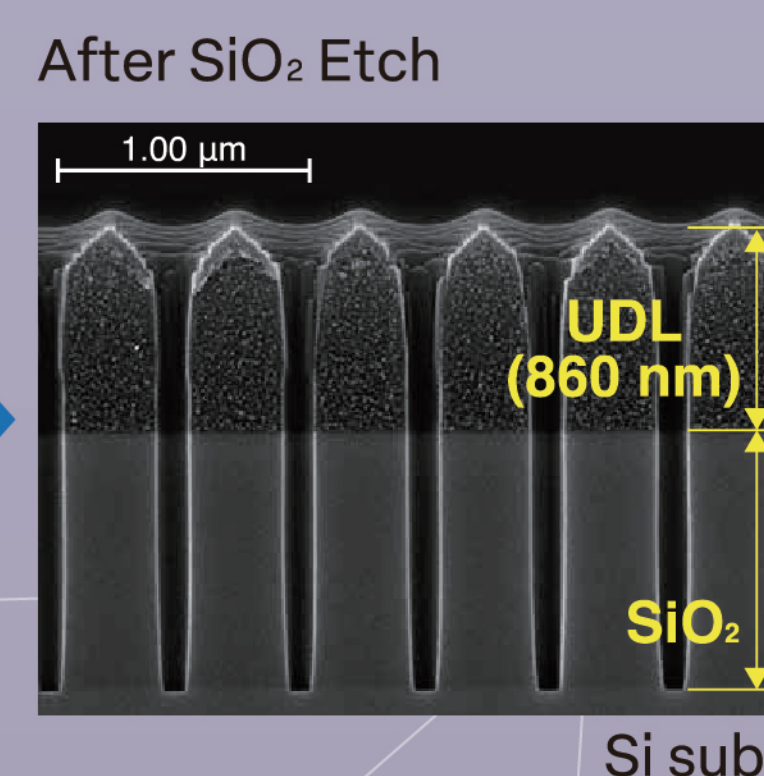
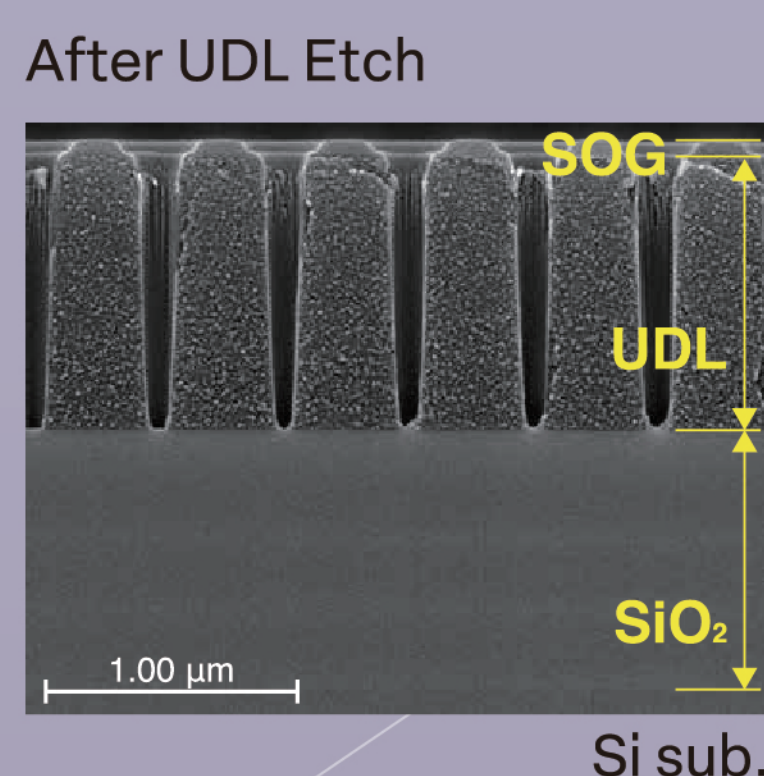
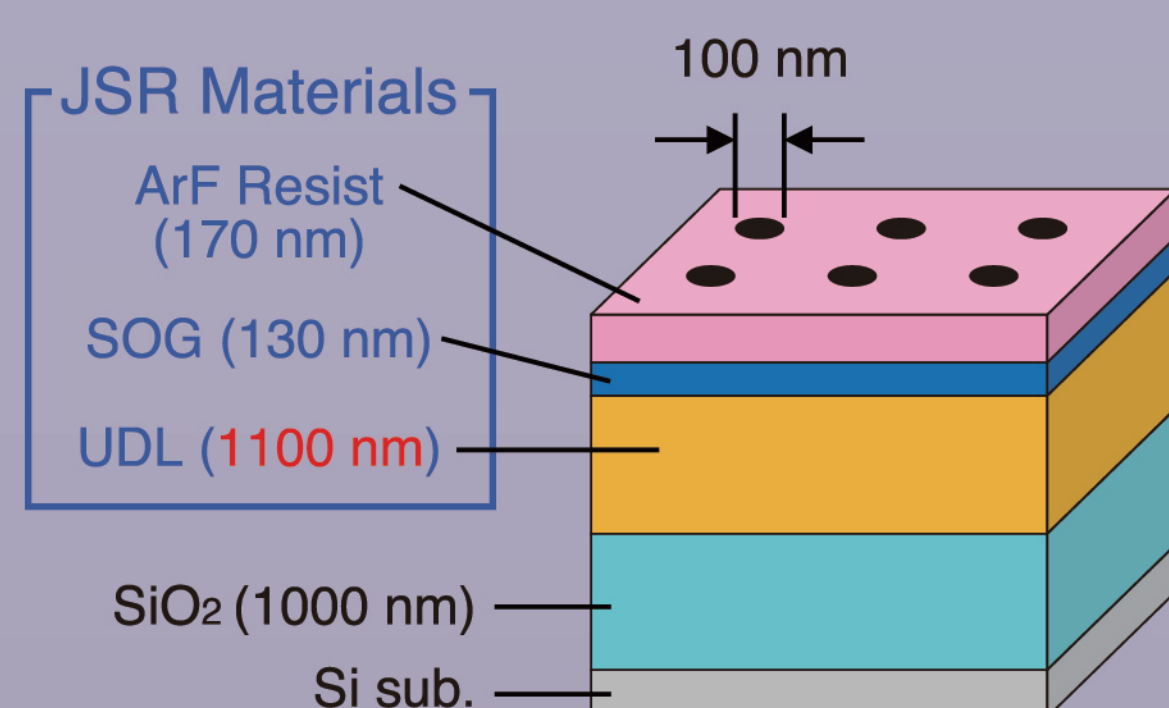
Gap-filling



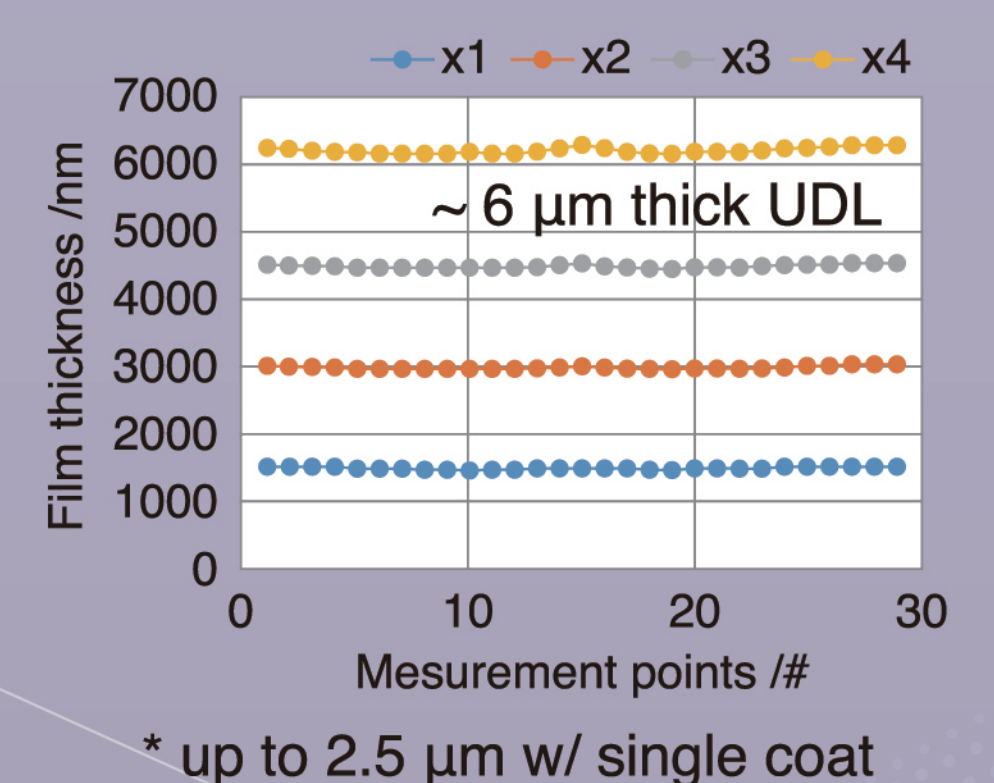
Thicker Application: UDL & SOG

Thick UDL

◆ Deep pattern transfer

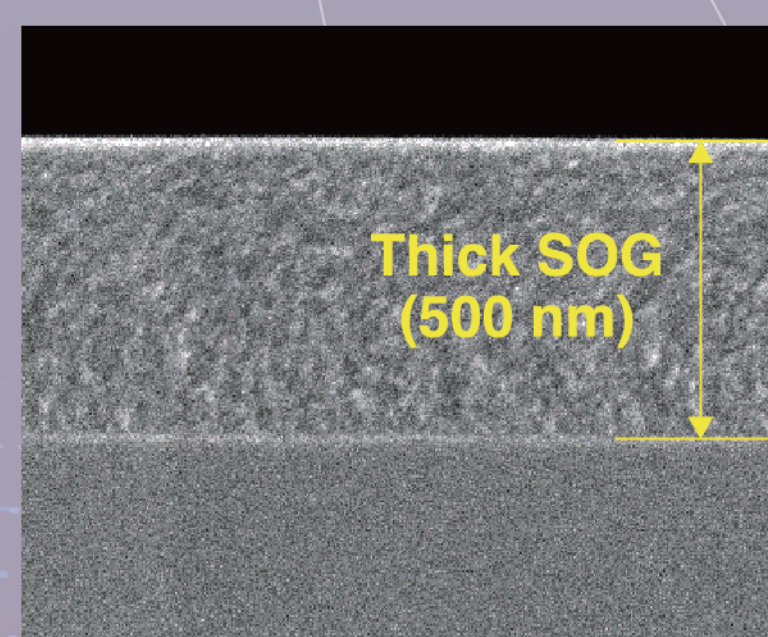
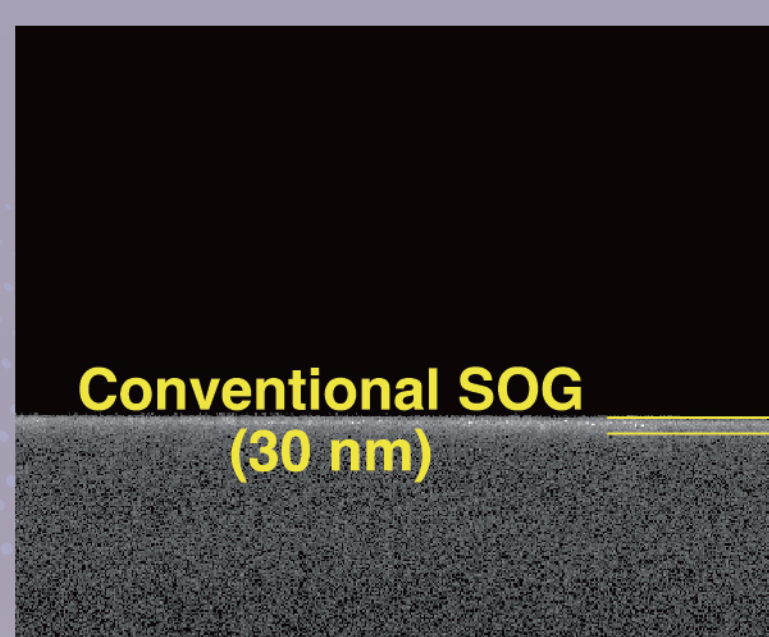


◆ Multiple coating

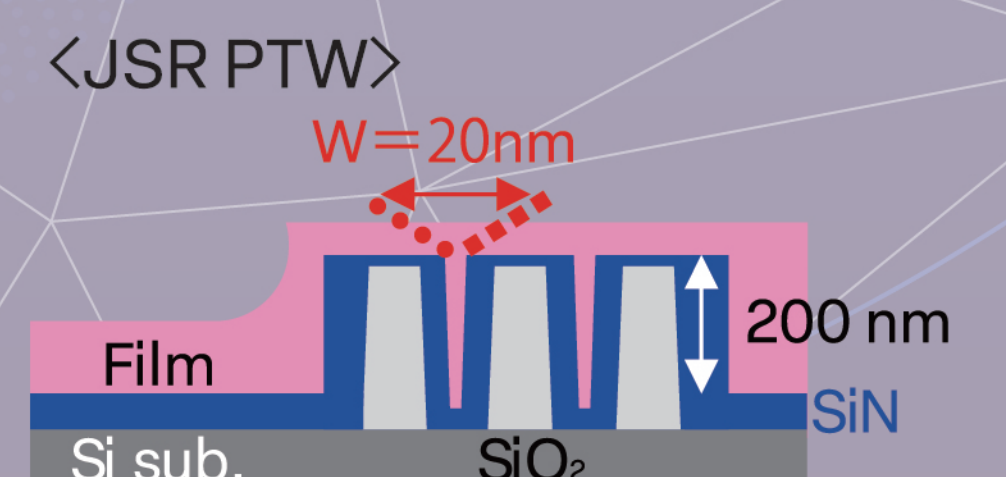
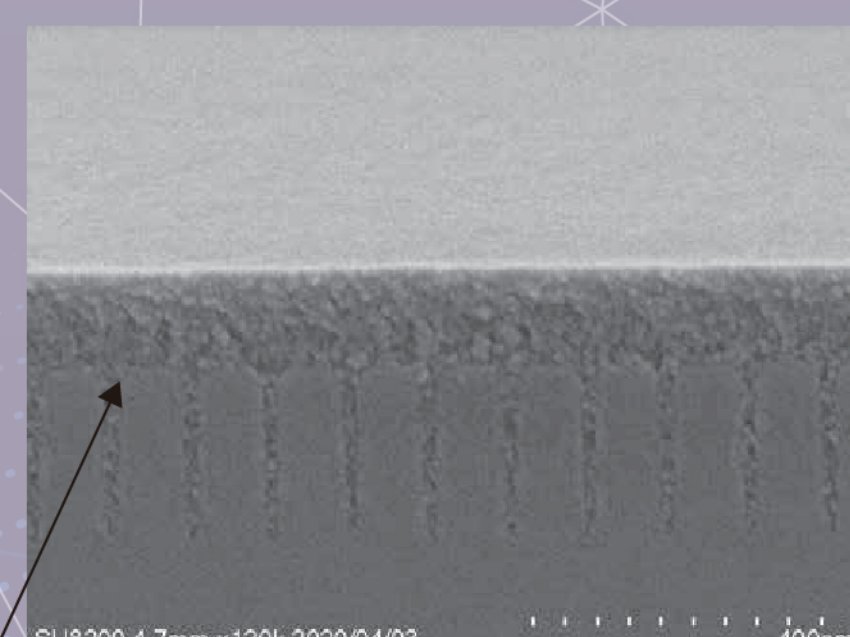


Thick SOG

◆ X-SEM of coating films



◆ Gap-filling



Good gap-filling and surface roughness